

ABSTRACT

The information processing apparatus (5) includes an information acquisition section (500) configured to acquire operating condition information including operation conditions of a substrate processing apparatus (2) including a substrate holder (241); and
5 a state prediction section (501) configured to predict substrate-holding-mechanism state information corresponding to the operating condition information by inputting the operating condition information to a learning model that has been generated by machine learning that causes the learning model to learn a correlation between the operating condition information and the substrate-holding-mechanism state information indicating a
10 state of the substrate holding mechanism (241a, 241c, 241e) when the substrate processing device (2) operates under the operating conditions indicated by the operating condition information.

FIG. 15